



# Electronic Filing System (EFS) Data Electronic Patent Application Submission USPTO Use Only

EFS ID:

63071

Application ID:

10680783

Title of Invention:

HIGH-PRESSURE CHAMBER FOR A SEMICONDUCTOR WAFER

First Named Inventor:

William Jones

Domestic/Foreign Application:

**Domestic Application** 

Filing Date:

2003-10-06

Effective Receipt Date:

2004-06-22

Submission Type:

Information Disclosure

Statement

Filing Type:

Confirmation number:

5859

**Attorney Docket Number:** 

NONE

**Total Fees Authorized:** 

Digital Certificate Holder: cn=Thomas B. Haverstock,ou=Registered Attorneys,ou=Patent and

Trademark Office,ou=Department of Commerce,o=U.S. Government,c=US Certificate Message Digest: ab4bce6b9127819148fc68a1715a12c75de85264



#### **TRANSMITTAL**

Electronic Version v1.1
Stylesheet Version v1.1.0

Title of Invention

HIGH-PRESSURE CHAMBER FOR A SEMICONDUCTOR WAFER

**Application Number:** 

10/680783

Date:

2003-10-06

First Named Applicant:

William D.

Confirmation Number:

5859

Attorney Docket Number:

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Submitted by:	Elec. Sign.	Sign. Capacity	
Thomas B. Haverstock Registered Number: 32571	/tbh/	Attorney	

Documents being submitted

Files

us-ids

SSI04001-usidst.xml

us-ids.dtd

us-ids.xsl

Comments



## **ELECTRONIC INFORMATION DISCLOSURE STATEMENT**

Electronic Version v18
Stylesheet Version v18.0

Title of Invention

HIGH-PRESSURE CHAMBER FOR A SEMICONDUCTOR WAFER

**Application Number:** 

10/680783

**Confirmation Number:** 

5859

First Named Applicant:

William Jones

Attorney Docket Number:

Search string:

(5186594 or 5769588 or 5906866 or 5975492

or 6122566 or 6355072 or 6454519 or 20030205510 or 20040020518 ).pn.

### **US Patent Documents**

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
	1	5186594	1993-02-16	Toshima et al.			
	2	5769588	1998-06-23	Toshima et al.			
	3	5906866	1999-05-25	Webb			
	4	5975492	1999-11-02	Brenes			
	5	6122566	2000-09-19	Nguyen et al.			
	6	6355072	2002-03-12	Racette et al.	B1		
	7	6454519	2002-09-24	Toshima et al.	B1		

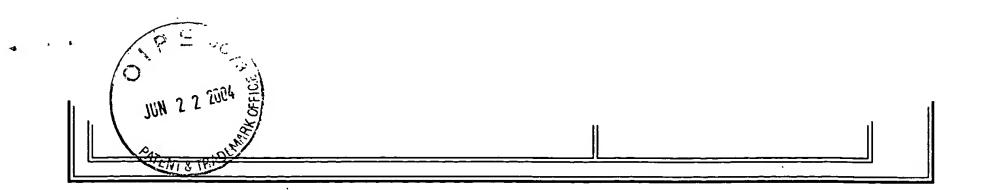
## **US Published Applications**

Note: Applicant is not required to submit a paper copy of cited US Published Applications

init	Cite.No.	Pub. No.	Date	Applicant	Kind	Class	Subclass
	1	20030205510	2003-11-06	Jackson	A1		
	2	20040020518	2004-05-02	DeYoung et al.	A1		

## Signature

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